

Fig.1: M-FSM45

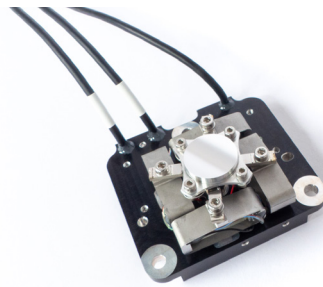


Fig.2: P-FSM150S

REFERENCE	TECHNOLOGY	ACTUATOR TYPE	POSITION SENSORS	ANGULAR RANGE	RES. FREQ. ⁽⁴⁾	MIRROR SUBSTRATE	MIRROR COATING	REFLECTIVITY	RWE ⁽¹⁾
P-FSM35XS-SiO2-15mm	Piezoelectric	APA®	Strain gauges	+/- 2,5 mrad	890 Hz	SiO2 Φ15mm	Aluminum	> 85% [300nm to 700nm]	λ/10
P-FSM35XS-SiC-17mm	Piezoelectric	APA®	Strain gauges	+/- 2,5 mrad	1390 Hz	SiC Φ17mm	Silver or Gold	> 95% [450nm to 2300nm]	λ/20
P-FSM35XS-SiC-30mm	Piezoelectric	APA®	Strain gauges	+/- 2,5 mrad	1270 Hz	SiC Φ30mm	Silver or Gold	> 95% [450nm to 2300nm]	λ/20
P-FSM60SM-SiO2-15mm	Piezoelectric	APA®	Strain gauges	+/- 6 mrad	1350 Hz	SiO2 Φ15mm	Aluminum	> 85% [300nm to 700nm]	λ/10
P-FSM60SM-SiC-17mm	Piezoelectric	APA®	Strain gauges	+/- 6 mrad	1440 Hz	SiC Φ17mm	Silver or Gold	> 95% [450nm to 2300nm]	λ/20
P-FSM150S-SiO2-15mm	Piezoelectric	APA®	Strain gauges	+/- 9 mrad	750 Hz	SiO2 Φ15mm	Aluminum	> 85% [300nm to 700nm]	λ/10
P-FSM150S-SiC-17mm ⁽³⁾	Piezoelectric	APA®	Strain gauges	+/- 9 mrad	750 Hz	SiC Φ17mm	Silver or Gold	> 95% [450nm to 2300nm]	λ/20
M-FSM45-SiO2-15mm	Magnetic	MICA™	Eddy currents	+/- 1,8°	100 Hz	SiO2 Φ15mm	Aluminum	> 85% [300nm to 700nm]	λ/10
M-FSM45-SiC-17mm	Magnetic	MICA™	Eddy currents	+/- 1,8°	100 Hz	SiC Φ17mm	Silver or Gold	> 95% [450nm to 2300nm]	λ/20
M-FSM45-SiC-HP-17mm ⁽³⁾	Magnetic	MICA™	Eddy currents	+/- 1,8°	100 Hz	SiC Φ17mm	Dielectric	> 99,5% at 1064 nm	λ/20
M-FSM62-SiC-30mm	Magnetic	MICA™	Eddy currents	+/-5° ⁽²⁾	90 Hz	SiC Φ30mm	Silver	> 95% [450nm to 2300nm]	λ/20

(1) Reflected Wave Front Error, measure at $\lambda = 633\text{nm}$ and 0° angle of incidence at mirror manufacturing

(2) Limited to +/- 2,5° with internal ECS sensors option

(3) Space constellation version available for optical communication

(4) Actuation resonance frequency

> Related drive electronics



Fig.3: CCBu20



Fig.4: CCBu40



Fig.5: MCSA480



Fig.6: MCLA18



Fig.7: ECS 45



Fig.8: CMAμ10